

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant: Hiroyuki MATSUURA

CONFIRMATION NO.: 8170

U.S. Serial No.: 10/563,208

Group Art Unit: 3743

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Examiner: Christopher D. Pilling

For: LOW PRESSURE PROCESSING SYSTEM, LOW PRESSURE PROCESSING
METHOD, AND PRESSURE CONTROL VALVE

FOURTH INFORMATION DISCLOSURE STATEMENT

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

Pursuant to the duty of disclosure under 37 C.F.R. 1.56, Applicant encloses an Information Disclosure Citation Form (PTO-1449) which lists a Korean Office Action issued on September 27, 2009 being submitted herewith. No copies of the documents listed in the office action are enclosed because they were cited previously in Applicant's first Information Disclosure Statement filed with this application.

Applicant certifies under 37 C.F.R. 1.97(e)(1) that the item of information contained in this Information Disclosure Statement was first cited in any communication from a foreign patent office in a counterpart foreign application not more than three months prior to the filing of the information disclosure statement.

It is respectfully requested that the cited document be considered by the Examiner, that it be made officially of record therein, and that the document be listed on the face of any patent which may issue from this application. No fees are believed due with this filing, however, if for any reason fees are required relative to this filing, the Commissioner is authorized to charge the fees to SGR Deposit Account No. 02-4300.

Respectfully submitted,
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